

Fig.3

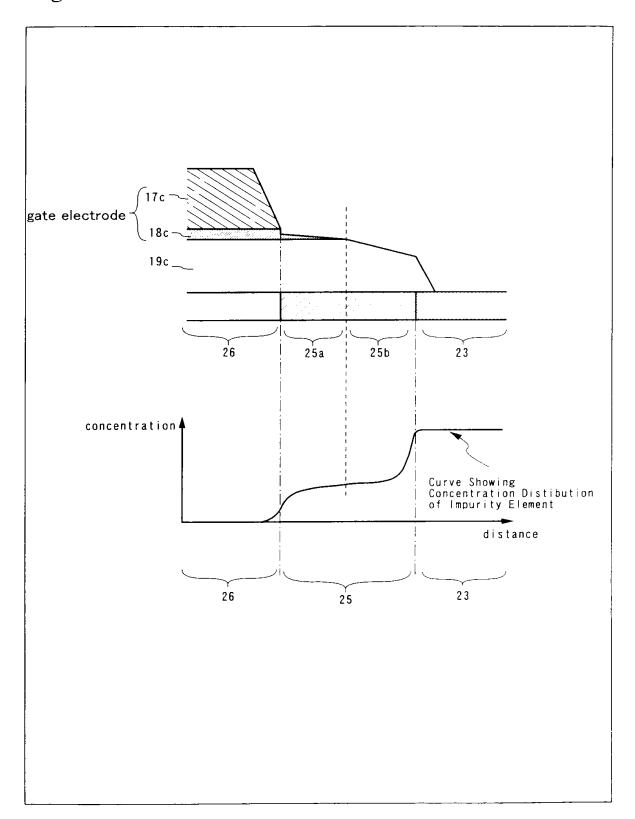
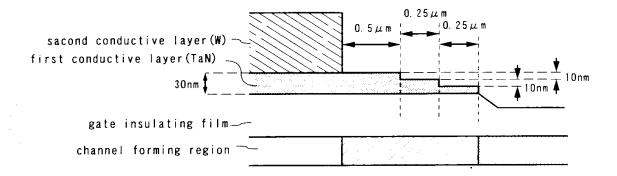


Fig.4



Schematic Structual View in Simulation

- P Conc. [/cm3]

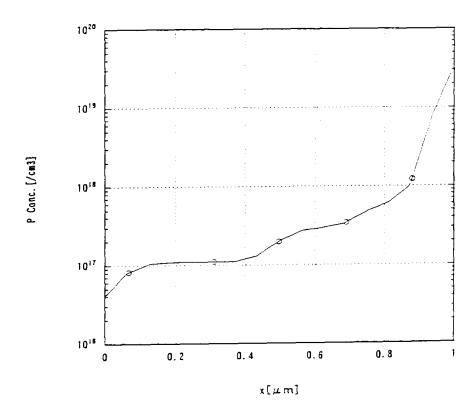
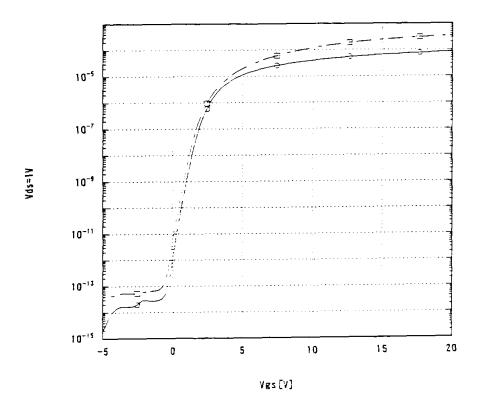
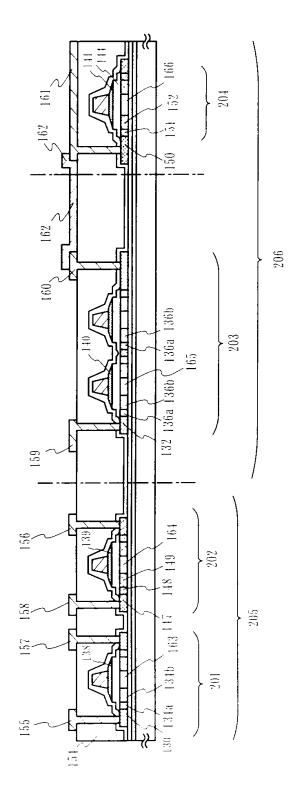
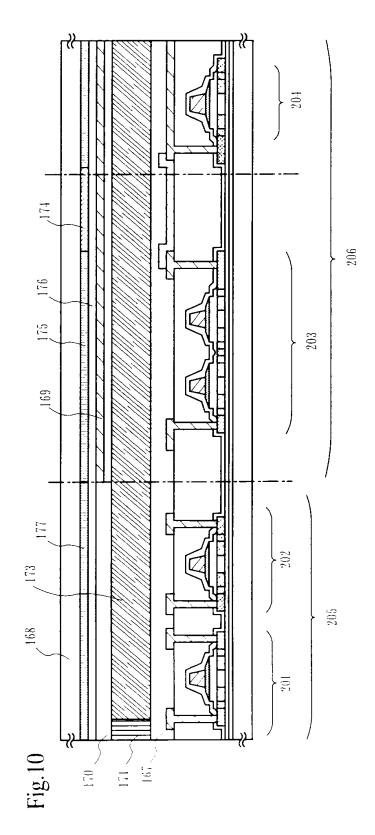


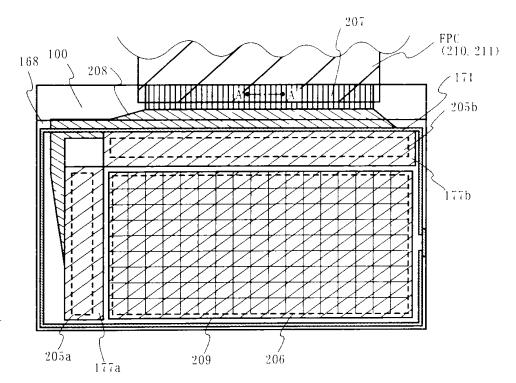
Fig. 6

--- Vds=1V
--- Vds=14V

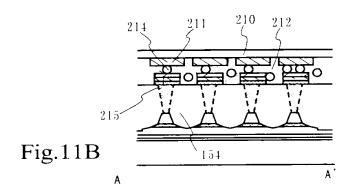


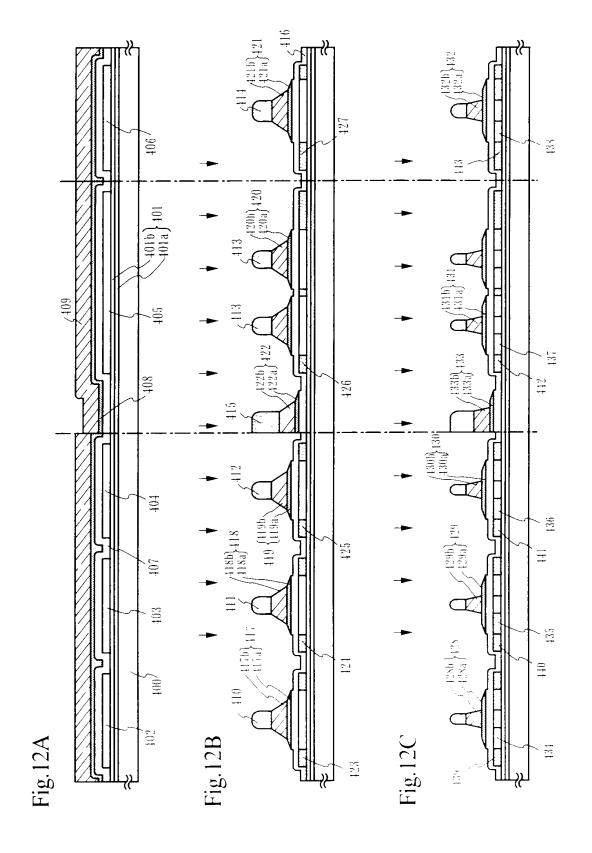












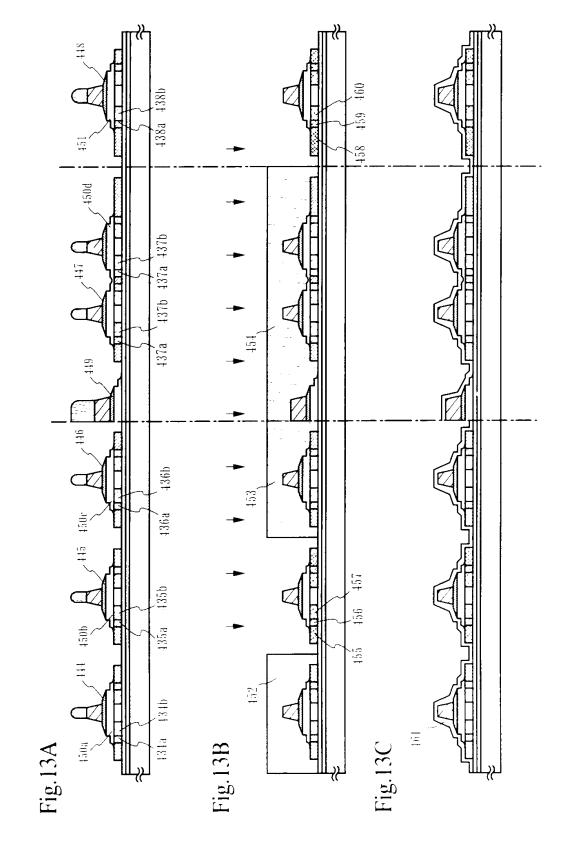


Fig. 14

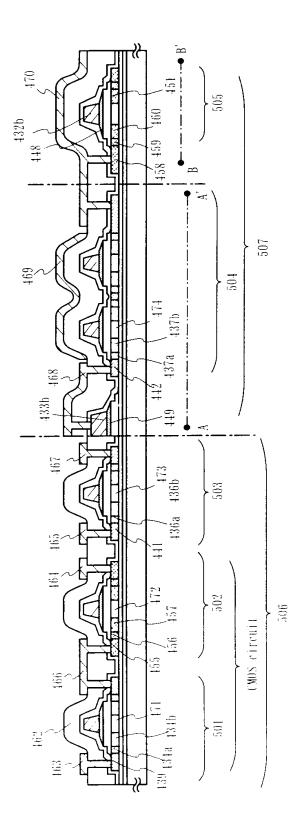
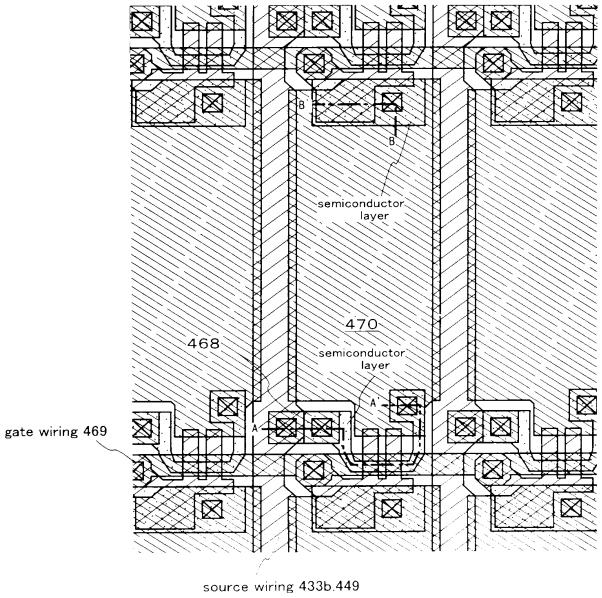


Fig.15



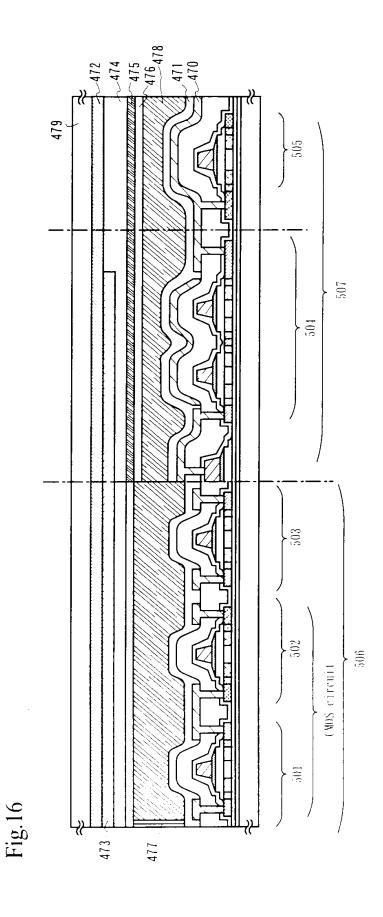
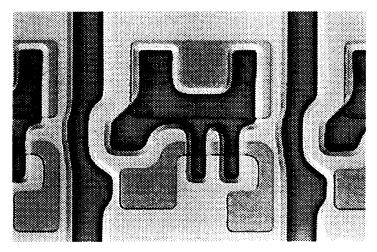


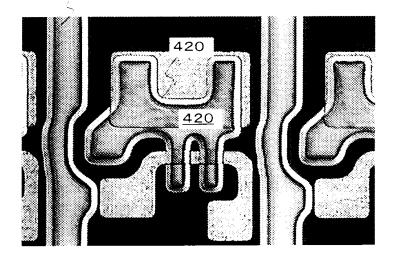
Fig. 17A



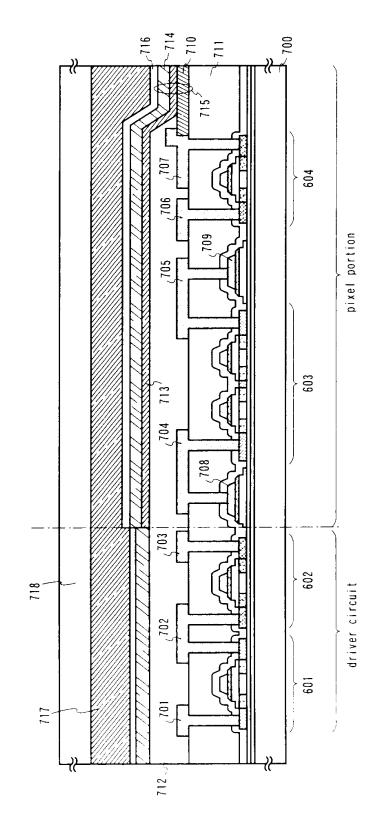
ICP power: 500W, RF power: 150W, chamber pressure: 1.0Pa $Cl_2=25sccm$, $CF_4=25sccm$, $O_2=10sccm$

Fig.17B

422



ICP power: 500W, RF power: 20W, chamber pressure: 1.0Pa Cl_2 =30sccm, CF_4 =30sccm



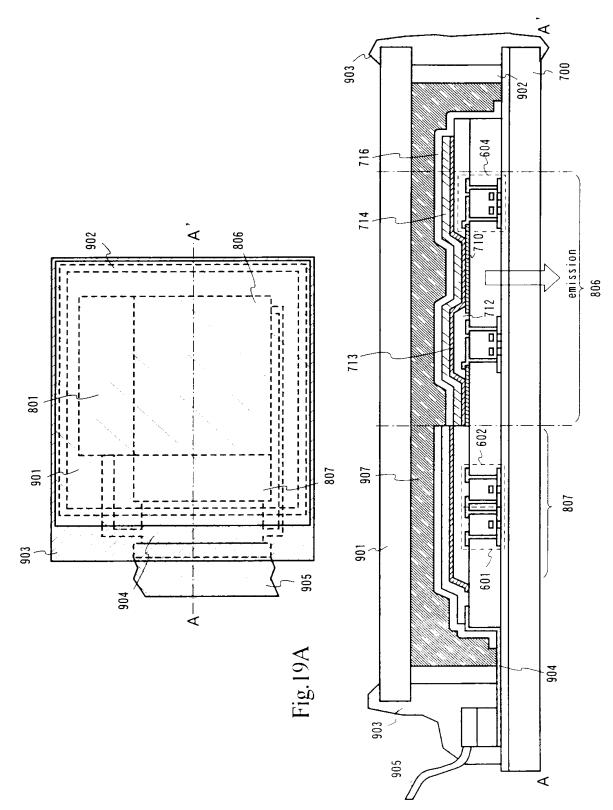
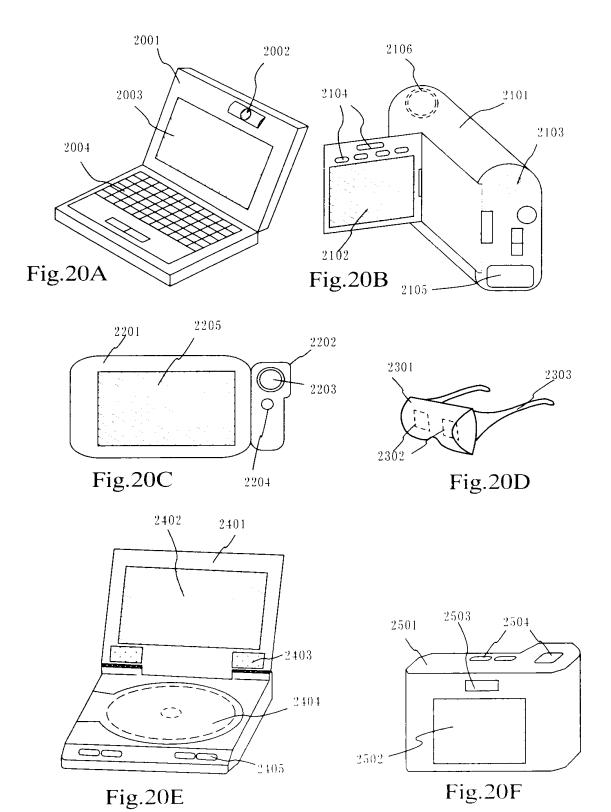


Fig.19B



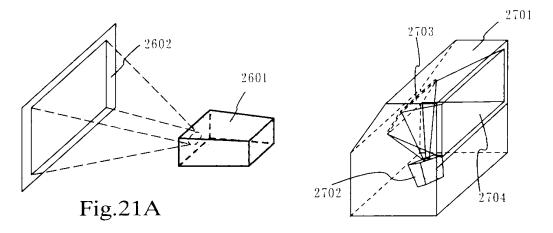


Fig.21B

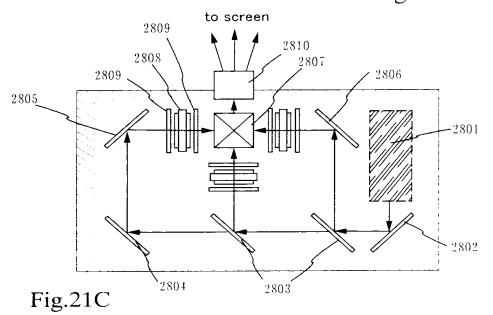
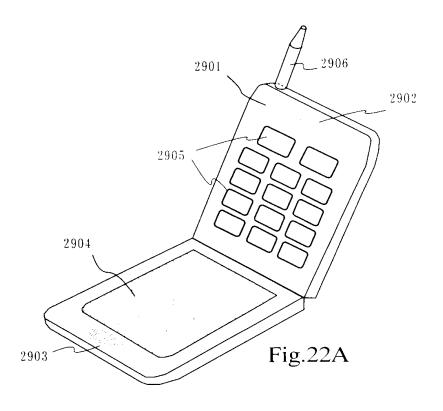
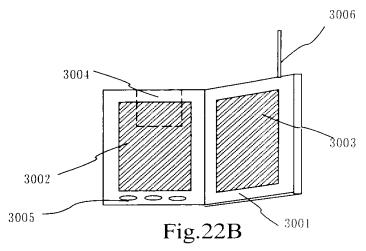
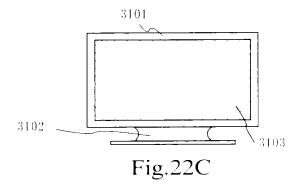


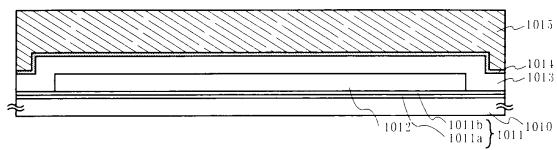
Fig.21D

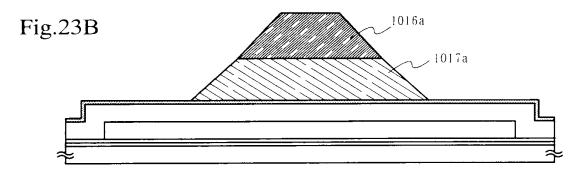


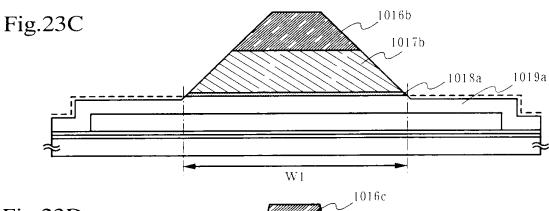












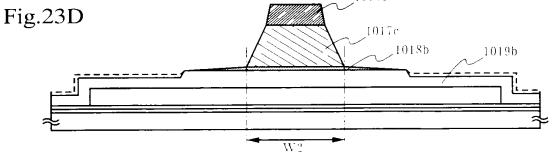
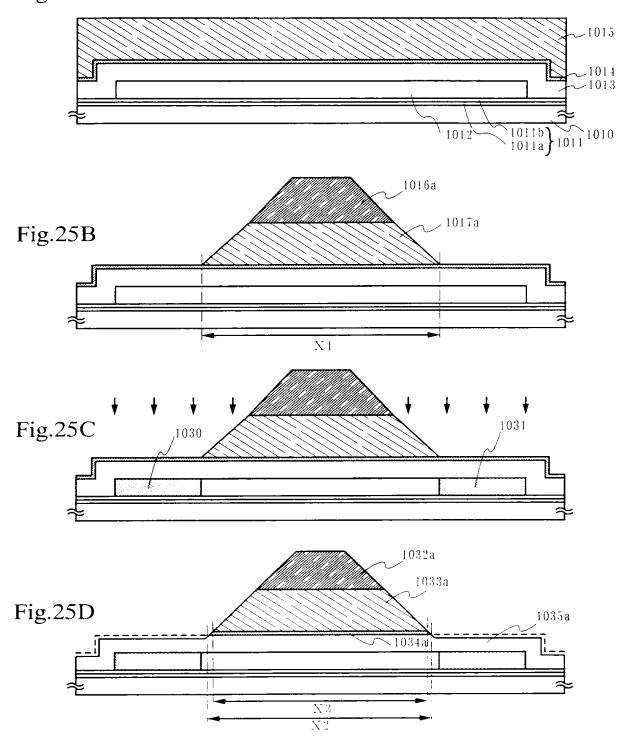
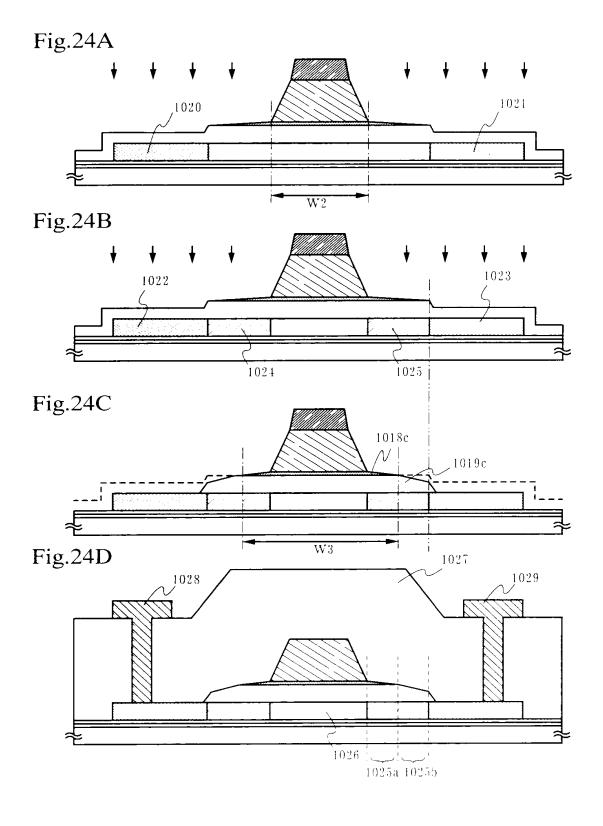
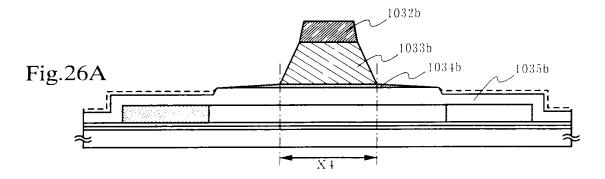
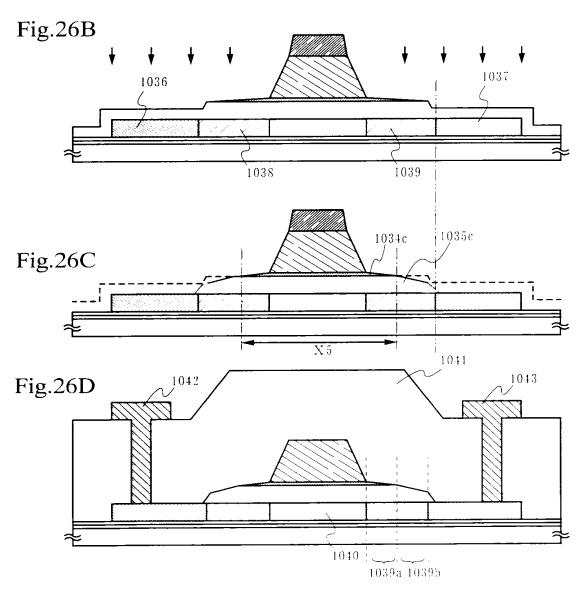


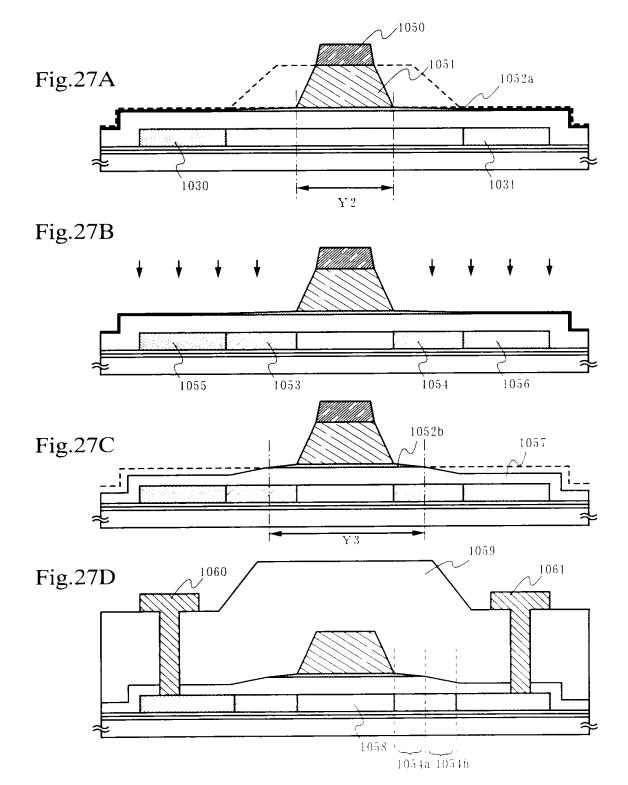
Fig.25A











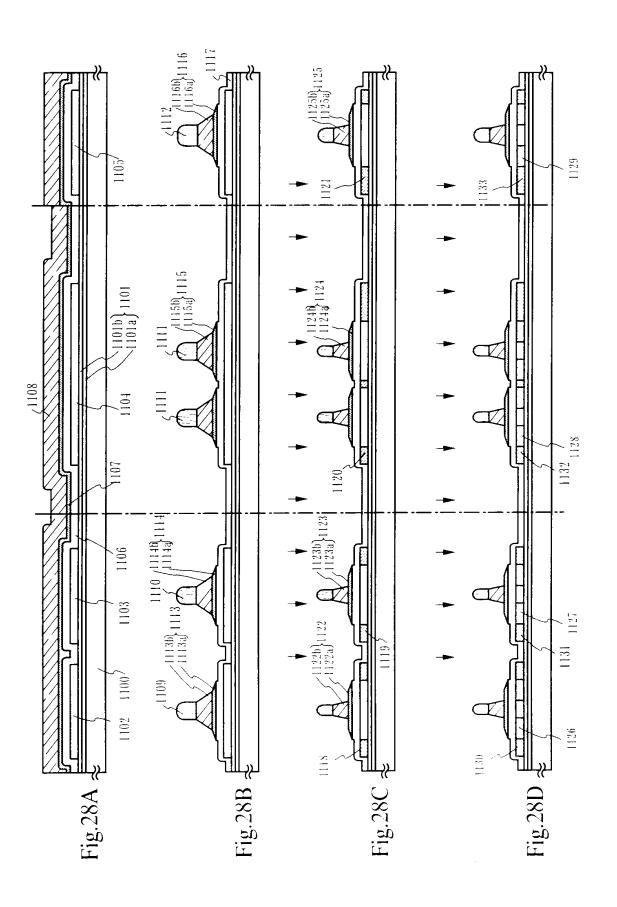
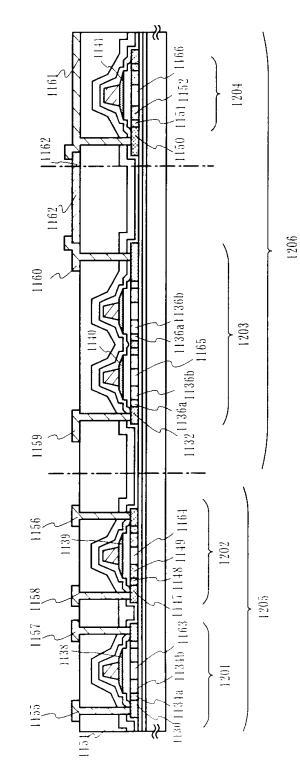


Fig.30



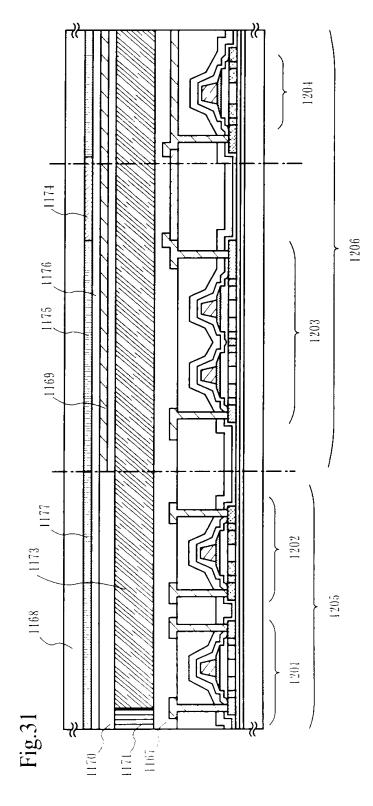


Fig.32

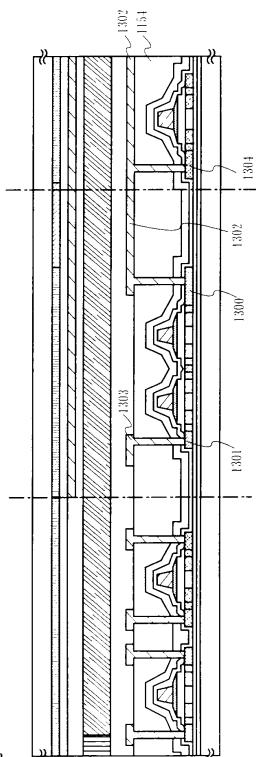


Fig.33

